



2-D Materials based Electronic Devices

Guest Editor:

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Message from the Guest Editor

Because of their atomically thin dimensions and excellent electrical and optical properties, there has been intense research efforts directed at the growth and fundamental properties of two-dimensional (2-D) materials. This Special Issue will showcase research papers, review articles, and short communications related to electronic/optoelectronic devices fabricated using this class of material. Their intrinsic properties are a result of confinement in one dimension and a relatively large surface area, which allows for stacking different materials in a layer-by-layer growth. It also allows engineering materials of different compositions to form hybrid composites with unique properties to enable diverse functionalities. 2D materials of interest include but are not limited to graphene, metal di- and tri-chalcogenides, etc. This Issue seeks to highlight a wide range of 2-D materials-based device applications ranging from field effect transistors, and sensors, to applications in plasmonics and photonics.





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Message from the Editor-in-Chief

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